



IFW 1765

Docket No.: 10191/1614

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Inventors : Richard SPITZ et al.  
Serial No. : 09/720,720  
Filed : February 28, 2001  
For : METHOD FOR ELIMINATING DEFECTS IN SILICON  
ELEMENTS THROUGH SELECTIVE ETCHING  
Examiner : TRAN, Binh  
Art Unit : 1765  
Confirmation No. : 3872

Mail Stop Amendment  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as first class mail in an envelope addressed to: Mail Stop Amendment, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on

Date: September 7, 2006

Reg. No. 36,197

Signature: \_\_\_\_\_

Jong H. Lee

**AMENDMENT**

SIR:

This Amendment addresses the Office Action mailed June 22, 2006, and it is respectfully requested that the above-identified application be amended as follows.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 6 of this paper.